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APPLICANT  
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## U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO	DATE	NAME	CLASS	SUBCLASS	FILING DATE
EF	5,248,876	9 28 1993	Kerstens et al.			
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EXAMINER'S INITIALS	PATENT NO	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
CR	EP0871052A1	10 14 1998	Europe				

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EF	"Projection X-Ray Lithography Using Arrays of Zone Plates", M. Feldman, Electrical & Computer Engineering Department, pp. 136-144.
EF	"Zone-plate-array lithography in the deep ultraviolet", Ihsan J. Djomehri et al., American Vacuum Society, 1998, pp. 3426-3429.
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